

The 3rd Korea-Japan Workshop on KAGRA December 21 – 22, 2012 Sogang University, Seoul, KOREA

Overview on Current Status of KAGRA

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Outline: O Brief review of KAGRA O Current status of KAGRA



Location (Kamioka)



Key features of KAGRA

Underground Reduce seismic noise

Cryogenic Mirror

Reduce thermal noise





Resonant sideband extraction (RSE) Interferometer Optimize quantum noise

Ground motion in Kamioka mine





Cryogenics System



RSE interferometer



Target sensitivity of KAGRA



Expected event rate for NS-NS coalescence

Inspiral range: 167 Mpc (the same definition as LIGO/Virgo)

Inspiral rate per galaxy $118^{+174}_{-79} \,\mathrm{Myr}^{-1}$

Expected event rate $9.8^{+14}_{-6.6} \text{ yr}^{-1}$

Schedule of KAGRA



i-KAGRA — b-KAGRA —

- Training for km-scale IFO.
- Sorting out the problems involved in KAGRA
- Short observation will be done

- Introduce Full Type-A SAS, Cryogenic and RSE Technique.
- Realize the targeted sensitivity and observation.

Organization



Current status of the tunnel excavation. 2012/12/15

- Both access tunnels have completed.
- Y end area except the 2nd floor has completed.
- The current progress of the Y arm tunnel is 700m.
- Excavation of the Center area (not including the 2nd floor) has been finished.
- Excavation of the Xarm starts soon.



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Center experiment room A







Center experiment room A (Reverse angle photo)





Panorama photo from BS position.









X-front cryostat room





Y-front cryostat room







From Laser booth to BS







Yarm tunnel 400m from Yend



2012/10/26





KAGRA Vacuum System

2. Beam tube

Beam tube (478 of 12-m long and 0.8 m in diameter); 426 tubes completed, so far.

"surface passivation by electro-polish followed by baking" outgassing rate; 10⁻⁸ Pa m³ m⁻² s⁻¹, or lower surface roughness; Rmax 3 μm, Ra 0.5 μm

"*mirror finish by Electro-Chemical Buffing (tubes in the mid 800-m region)*" surface roughness; Rmax 0.2 μm, Ra 0.03 μm

"flange connection with metal O-ring (silver plated)"; erosion proof by humidity test



KAGRA Vacuum System

3. Optical baffles in beam tubes

Every 12-m, or longer, along the arm, 40-mm in height, 50-degree tilted

** laser machining is tested for making serration edges
** "DLC coating" and "NiP plating" are examined to be chosen.
"optical absorption coefficient"
"angular distribution of reflectivity"

"outgassing rate"



KAGRA Vacuum System



Cryogenics : Cryostat assembling and performance test



Dressing partition of No.1 Cryostat



Al sphere for an initial cooling test of mirror suspension





Ceiling part of 8K shield

- Assembling of cryostats and preparation of performance tests are in progress in the TOSHIBA Keihin Factory.
- Basic test items
 - Cooling time, minimum attainable temperature under various heat loads.
- Specific test items
 - Cryostat No.1 : Cooling test of ϕ 105 Al sphere without DLC.
 - Cryostat No.2 : Cooling test of ϕ 105 Al sphere with DLC.
 - Cryostat No.3 : Vibration measurement of 8K shield using interferometer(ICRR) and accelerometer(Roma Univ.)
 - Cryostat No.4 : Cooling test of a scaled preliminary model of cryogenic payload.

Cryogenics : Duct shield

(17m vacuum duct + cryo-pipe)





- One set of 17m duct shield is manufactured by TOSHIBA in 2012-2013.
- An investigation for shorter cryo-pipe is started by the requirement of cost reduction.



Investigation of shorter cryo-pipe



Cryogenics: 4K cryocooler unit



4K cryocooler unit and set of displacement meter.



Inner structure of cryocooler unit.





3D plot of 8K cooling path. Voltage to displacement conversion factor is 10⁻⁵ m/V. Moving average of 0.2 sec was applied.

- 4K cryocooler units with vibration reduction mechanism are manufacturing.
 - 5 units in 2011FY and 9 units in 2012FY.
- Cooling power of the cryocooler satisfied the requirement.
- Vibration level was improved by a reinforcement of support structure.

Cryopayload

Sapphire fiber with nail head to suspend sapphire mirror Moltech GmbH and IMPEX GmbH (Germany) delivered !

Quality check is in progress.





Cryopayload

DLC coating (black coating) makes initial cooling time twice times shorter.

In ICRR, this DLC effect is observed in experiment. Moreover, similar experiments will be conducted in cooling test of KAGRA cryostat in Toshiba.



Status of Vibration Isolation Subsystem



Current status

The pre-isolaor prototype is working with digital control system in Kashiwa.
Final assembly of the GAS filters is going in Akeno.
The payload prototype is ready for assembly.

•6 pre-isolators are in production at the facility.



Control test of the inverted pendulum. Some resonances were damped effectively.



Assembly jig for the mirror suspension in production.





Tuning of the inverted pendulm. The present resonant frequency is 130mHz.



Assembling of the intermediate mass.

Vibration isolation

• See Takahashi-kun's talk for more details.

Current status (Fabrication)

- Procedure for making a contract for polish and coating for BS has been started.
- Procedure for making a contract for polishing RMs and SRMs has been started.
- Preparation of ITMs for iKAGRA has been started; the use of iLIGO mirrors be comes possible by changing the wedge angle.
- Polished MC mirror substrates have been sent to LMA and inspected; the flat mirrors are OK but the curved mirror should be sent back to Japan to measure its ROC.

Sapphire mirrors

- Large c-axis sapphire crystals have been obtained.
- Pathfinder polish of sapphire is being progressed; it seems good for the 10-cm diameter crystal.
- ESR measurement to investigate the cause of the optical absorption has been started at Prof. Ono's lab at Toyama Univ.







Laser

• See Mio-san's talk.

Main interferometer

• See also Miyoki-kun and Aso-kun's talks.

Detector characterization

• See Hayama-kun's talk.



Input/Output Optics subgroup





Input/Output Optics subgroup

Reference cavity test will start soon!!



AOS tasks:

- Stray Light Control (SLC)
- ETM Transmission Monitor Telescopes
- Optical Levers (OpLevs)
- Monitors (CCD cameras) and Illumination
- Viewports
- Automatic Targets

 Other subsystems that will be useful for the commissioning phase (e.g. Beam Profiler for large spot size)





Stray-light Control

• Baffle design (mechanical and optical) is ongoing.

• Black material for the baffles are under investigation; Diamond-like carbon (DLC), Ni-coat...



Optical Levers

• Prototype tests are ongoing; combination of a fiber light-source and a position sensitive detector is now the first candidate.

• More discussion will be required for the design of OpLevs for bKAGRA main mirrors (in cryostats).

Viewports

- Prototype tests of #2 are ongoing.
- Purchase list (planned) is as follows.

Categories	Specification	Qty.
#1 Special	1064nm AR	2
	1064/532nm AR	2
#2 For OpLevs	ICF152	30
	ICF70	10
#3 General purpose	ICF203	100

Auxiliary optics

• See Ando-kun's talk for more details.

KAGRA Recent work for DGS

- Observation at CLIO with RT system for detector characterization. Lock acquisition, calibration and some software for data analysis. 13 hours data including 2 hours continuous lock.
- A new larger room at Kamioka Hokubu-kaikan for 7 racks RT system
- Making a signal list at ADC and DAC
 - Listed ~900ch/3200ch to estimate more accurate No. of ADC, DAC, IO chassis and RT-PC
- Making a location list for ADC, DAC, IO chassis and RT-PC on 19 inch racks
- Visiting LIGO to see km scale control system, estimating the total number of RT PCs, IO chassis, electronics etc.

KAGRA Digital control system for Pre-Isolator



Preparation for mass production of electronics for digital system

Example of electronics: AA filter

- 6 layers circuit board
- 8ch Differential input/output with buffer
- 3order 10kHz LPF, 65536Hz notch
- 0.2A/board
- 8 D-SUB 9pin connectors as signals input, total 32ch
- D-SUB 3pin connector as DC power supply input

Asking several companies for mass production of electronics

- Design boards -> by each subsystem
- 2. Making boards, soldering electronic parts
- 3. Making chassis
- 4. Putting them into chassis
- Inspection -> but probably limited test due to technological difficulty, limited budget

Lecture for subsystem: "How to make a circuit for KAGRA" in October

Data management & Data analysis

• See Tagoshi-kun's talk.